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(54) **Method of fabrication of an infrared radiation detector and more particularly an infrared sensitive bolometer**

(57) A method of fabricating an infrared sensitive bolometer, comprising the steps of:

- forming a sacrificial layer (11, 12 or 43) on a substrate (10 or 41);
- patterning said sacrificial layer (11, 12 or 43);
- depositing or growing a layer (13 or 42) consisting essentially of polycrystalline SiGe on said sacrificial layer;
- depositing an infrared absorber (49) on said polycrystalline SiGe layer;
- removing the sacrificial layer (11, 12 or 43).

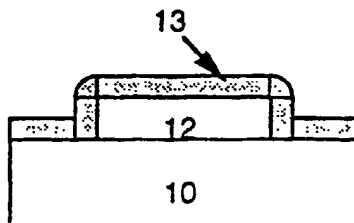


FIG. 1b

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Application Number
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The present search report has been drawn up for all claims			
Place of search THE HAGUE		Date of completion of the search 24 August 1998	Examiner Visscher, E
<p>CATEGORY OF CITED DOCUMENTS</p> <p>X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document</p> <p>T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document</p>			

ENCL. FORM 1503 03/92 (PUB.01)



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DOCUMENTS CONSIDERED TO BE RELEVANT			
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